

<b>Notice of References Cited</b>	Application/Control No. 10/600,886	Applicant(s)/Patent Under Reexamination SHEMESH, DROR	
	Examiner Zia R. Hashmi	Art Unit 2881	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-5,288,368	02-1994	DeMarco et al.	216/66
	C	US-			
	D	US-			
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	G	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Slevers et al. " Focused Ion Beam Process for Removal of Copper", Pub. No: US 2002/0195422 A1, publication date: December 26, 2002.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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